



1. Title:	Small Field Exposure Tool (SFET) Light Source Status
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3. Abstract body:

A small field exposure tool (SFET) has been built in Japan under the guidance of EUVA and Canon Inc. The light source of SFET has been developed at the EUVA Hiratsuka R&D center. The drive laser is a short-pulse, high-power KrF laser, developed by Gigaphoton Inc. and Komatsu Ltd., and the source target is a xenon jet. The light source, its characteristic performance and future developments will be presented in detail.

This work was supported by the New Energy and Industrial Technology Development Organization (NEDO), Japan.